

IPW



PATENT
Customer No. 22,852
Attorney Docket No. 04329.2622

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
)	
Gaku MINAMIHABA, et al.)	Group Art Unit: 2823
)	
Serial No.: 09/932,943)	Examiner: Lee, Hsien Ming
)	
Filed: August 21, 2001)	
)	
For: SLURRY FOR CHEMICAL)	
MECHANICAL POLISHING AND)	
METHOD OF MANUFACTURING)	
SEMICONDUCTOR DEVICE)	

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

REQUEST FOR RECONSIDERATION

In reply to the Office Action of April 20, 2004, with a period for response extending through July 20, 2004, Applicants respectfully request the Examiner's reconsideration in view of the remarks that follow:

Remarks begin on page 2 of this paper.